

# 2012 International Workshop On EUV Lithography

June 4-8, 2012

Sheraton Maui ▪ Maui, Hawaii

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## Award Ceremony



# Outstanding Contribution Award



Rupert Perera (Right) of EUV Technology is presented the Outstanding Contribution Award by Dr. Gregory Denbeaux (Right) of Univeristy of Albany.

# Poster Session Award



## Best Poster Award

### FIRST PLACE

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Dr. Hakaru Mizoguchi (Left) of Gigaphoton accepts, on behalf of his group, Best Poster Award for the poster paper. Award was presented by the session chair, Dr. Greg Denbeaux (Right) of University of Albany.

# Thank You!



Yan Borodovsky, Intel Corporation (Right) accepts award for his keynote presentation from Vivek Bakshi (left), Chair, EUVL Workshop.

# Thank You!



Soichi Inoue (Right), EIDEC, accepts award for his keynote presentation from Vivek Bakshi, Chair, EUVL Workshop.

# **GROUP PHOTOGRAPH**

## **2012 EUVL Workshop**



